

Form PTO-1449	U.S. Department of Commerce Patent and Trademark Office	Attorney Docket No. <u>5051-538DV2</u>	Serial No. To Be Assigned				
LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)		Applicants: Russell et al.					
		Filing Date: Concurrently herewith	GAU: unknown				
U.S. PATENT DOCUMENTS							
Examiner Initials		Document No.	Date	Name	Class	Subclass	Filing Date if Appropriate
	1	6,140,655	10/31/00	Russell et al.	250	492.2	
	2	6,057,223	05/02/00	Lanford et al.	438	618	
	3	5,959,358	09/28/99	Lanford et al.	257	762	
	4	5,899,740	05/04/99	Kwon	438	627	
	5	5,798,529	08/25/98	Wagner	250	492.2	
	6	5,766,379	06/16/98	Lanford et al.	148	537	
	7	5,188,705	02/23/93	Swanson et al.	156	643	
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes / No
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	8	Hariharaputhiran et al., Hydroxyl Radical Formation in H <sub>2</sub> O <sub>2</sub> -Amino Acid Mixtures and Chemical Mechanical Polishing of Copper, Journal of the Electrochemical Society, Vol. 147, No. 10, October 2000, pp. 3820-3826					
	9	Phillips et al., Channeling Effects During Focused-Ion-Beam Micromachining of Copper, J. Vac. Sci. Technol. A, 18(4), Jul/Aug 2000, pp. 1061-1065					
	10	Thaus et al., Development of Focused Ion-Beam Machining Techniques for Permalloy Structures, J. Vac. Sci. Technol B, 14(6), Nov/Dec 1996, pp. 3928-3932					

**Examiner:**

**Date Considered:**

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Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.